
ABSTRACT OF THE DISCLOSURE

A¹ A semiconductor manufacturing apparatus, for executing an exposure process upon filling a chamber with an inert gas, is provided with a supply unit that supplies clean, dry air for raising the concentration of oxygen in a maintenance area, and with a sensor for sensing oxygen concentration or ozone concentration in the maintenance area. When maintenance is carried out, the supply unit is actuated to raise the oxygen concentration in the maintenance area, thereby assuring the safety of workers. A maintenance cover includes a door switch for sensing that the cover has been opened, and actuation of the supply unit is started in accordance with the sensed state. Alternatively, the supply unit may be actuated on the basis of an input instruction.
